

IN THE CLAIMS:

Claims 1, 6, and 8 have been amended herein. All of the pending claims 1 through 8 are presented, pursuant to 37 C.F.R. §§ 1.121(c)(1)(i) and 1.121(c)(3), in clean form below. Please enter these claims as amended. Also attached is a marked-up version of the claims amended herein pursuant to 37 C.F.R. § 1.121(c)(1)(ii).

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1. (Amended) A testing apparatus for a wafer of semiconductor dice comprising:  
a first rigid support member for receiving a plurality of semiconductor dice in wafer form having  
a predetermined orientation, the first rigid support member having a plurality of contact  
members thereon and having a plurality of electrical connectors connected to the contact  
members for establishing communication with test circuitry;  
a second rigid support member for selectively engaging the first rigid support member to retain  
the plurality of semiconductor dice in wafer form therebetween, one of the first rigid  
support member and the second rigid support member including a single cavity for  
retaining the semiconductor dice in wafer form therein during testing; and  
a single biasing assembly including a single floating platform of a preselected area substantially  
sized for the single cavity, the single biasing assembly mounted to one of the first rigid  
support member and second rigid support member, the single biasing assembly sized for  
uniformly biasing the plurality of semiconductor dice in wafer form against the contact  
members.

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2. The apparatus as claimed in claim 1, wherein the plurality of semiconductor dice  
comprises a wafer.

3. The apparatus as claimed in claim 1, wherein the plurality of semiconductor dice  
comprises a die cluster in wafer form.

4. The apparatus as claimed in claim 1, wherein the single biasing assembly comprises the single floating platform in contact with an elastomeric polymer member.

5. The apparatus as claimed in claim 1, further comprising aligning devices for aligning the first rigid support member with the second rigid support member.

A3 6. (Amended) A wafer testing apparatus comprising:

a first rigid support member and a second rigid support member for receiving a wafer therebetween, one of the first rigid support member and second rigid support member including a single cavity for retaining the wafer therein during testing; a plurality of contact members formed on the first rigid support member for communicating with electrical connectors for connecting to external test circuitry; a single biasing assembly including a single floating platform having a preselected area substantially sized to correspond with the single cavity and an elastomeric member disposed on the second rigid support member, the single biasing assembly sized for uniformly biasing the wafer towards the contact members, the single floating platform directly supporting the wafer with the elastomeric member sandwiched between the single floating platform and the second rigid support member.

7. The apparatus as claimed in claim 6, further comprising an alignment device for aligning the first rigid support member and the second rigid support member with one another.

A4 8. (Amended) The apparatus as claimed in claim 6, further comprising an alignment device including a dowel on one of the first rigid support member and second rigid support member and a corresponding opening on the other of the first rigid support member and the second rigid support member.